

ABSTRACT

An apparatus for use in a building system includes at least one microelectromechanical (MEMs) sensor device and a processing circuit that are integrated onto a single substrate. The at least one MEMs sensor device is operable to generate a process value. The processing circuit is operable convert the process value to an output digital signal configured to be communicated to another element of a building automation system. The building automation system includes one or more devices that are operable to generate a control output based on set point information and process value information from one or more sensors.